

Date Searched: 6/22/2008

Databases Searched: USPAT, USPGPUB

Plurals: ON

Terms Searched:

L1 (mask\$3 or exposure or ebeam) near3 (data or pattern)

L2 (sort\$3 or order\$3 or priorit\$8) near15 1 near15 (field or scanstrip)

L3 716/19-21.ccls. or "707"/\$.ccls. or 700/117-121.ccls. or 250/492.1-492.3.ccls. or 430/4-5.ccls. or 378/34-35.ccls.

L4 2 and 3

Results: 43 hits

L5 (arrang\$6 or plac\$6) near15 1 near15 (field or scanstrip)

L6 3 and 5

Results: 71 hits

L7 raster\$8

L8

Mizuno; Fumio et al. US 6757621 B2 USPAT 702/35
Bennett; John R. et al. US 6675169 B1 USPAT 707/101
Kondo; Makoto US 6597002 B1 USPAT 250/492.2
Langston; Joseph C. et al. US 6051344 A USPAT 430/5
Enichen; William A. et al. US 6040095 A USPAT 430/5
Nakao; Shuji US 5962172 A USPAT 430/5
Okino; Teruaki US 5874198 A USPAT 430/296
Manabe; Yasuo et al. US 6350992 B1 USPAT 250/492.22
Muraki; Masato US 6104035 A USPAT 250/492.22
Suzuki; Shohei US 6087669 A USPAT 250/492.23
Manabe; Yasuo et al. US 6060717 A USPAT 250/492.22
Kusonose; Haruhiko et al. US 5296917 A USPAT 356/401
Frei; Joseph B. US 5189306 A USPAT 250/492.2
Tojo; Toru et al. US 4572956 A USPAT 250/492.2
Komatsuda, Hideki US 20040084632 A1 US-PGPUB 250/492.2
Nakasuji; Mamoru et al. US 6194102 B1 USPAT 430/5
Sohda; Yasunari et al. US 5387799 A USPAT 250/492.2
Ebinuma; Ryuichi et al. US 5365561 A USPAT 378/34
Isaacson; Michael et al. US 4659429 A USPAT 216/24

**With rasterization:

Muraki; Masato US 6104035 A
Kusonose; Haruhiko et al. US 5296917 A
Isaacson; Michael et al. US 4659429 A
Nakao; Shuji US 5962172 A

Databases Searched: EPO, JPO, IBM TDB, Derwent

Plurals: ON

Terms Searched:

L1 (mask\$3 or exposure or ebeam) near3 (data or pattern)

L2 (sort\$3 or order\$3 or priorit\$8 or arrang\$6 or plac\$6) near15 1 near15 (field or scanstrip)

Results: 71 hits

KOYAMA, MASAOKI JP 11087223 A

OSHIMA, TORU JP 09162101 A
WATANABE, TAKASHI JP 06310410 A
MIYAJIMA, MASAOKI JP 04288813 A
KUSUSE, HARUHIKO et al. JP 04237115 A
NAKASUJI M JP 11054392 A
HOSHINO H et al. JP 08321462 A
MANABE Y JP 07263323 A

HAYAKAWA, YOSHIHIRO JP 09293661 A
YODA, HARUO et al. EP 1387389 A2

Database Searched: IEE/IEEE XPlore

Terms Searched: (mask* or exposure or ebeam) <near/3> (data or pattern) <near/15>
(sort* or order* or priorit* or arrang* or plac*) <near/15> (field or scanstrip)

Results: Your search matched 0 of 1820465 documents